Kyoto's Event-Driven X-ray Astronomical SOI Pixel Sensor

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We are developing Silicon-On-Insulator Pixel (SOIPIX) Detectors



Features of SOI Pixel Detector



- Monolithic device. No mechanical bonding. Small pixel size.
- Fabricated with semiconductor process only and based on Industry Standard Technology. → High reliability and Low Cost.
- High Resistive fully depleted sensor (50um~700um thick) with Low sense node capacitance. → High S/N.
- In-pixel processing with CMOS circuits.
- No Latch up and very low Single Event cross section.
- Can be operated in wide temperature range (1K-570K).

SOIPIX MPW (Multi-Project Wafer) run Lapis Semiconductor 0.2 µm FD-SOI Pixel Process



Tracking Resolution of FPIX2 Proton Beam (120 GeV/c) test @FNAL

Two kinds of SOIPIX-DSOI detectors are used:

- FPIX2 x 4
 8 μm square pixel detector
- SOFIST1 x 2 20 µm square pixel detector



Achieved Less than 1 μm Position Resolution for high-energy charged particle first in the world .

(K. Hara et al., Development of Silicon-on-Insulator Pixel Detectors, Proceedings of Science, to be published)

X-ray Imaging System



X-ray CCDs as Standard Imaging Spectrometers at 0.3-10keV.

X-ray Photon Counting





- Detect an X-ray photon as one-by-one event.
- Measure position, energy and time of each

X-ray event.

Make exposures of ~10^4 times.

Map of the number of X-ray events

Histogram of energy (electron number) of X-ray events



Limitation due to low time resolution of CCD (~Isec)

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- Unable to make good use of the performance of large collecting area and high angular resolution of the latest mirrors.
 - Event pileup occurs. Photon counting is impossible.



- Unable to resolve fast variability of compact objects such as blackholes and neutron stars.
- Unable to apply anti-coincidence technique
 - Unable to make use of the excellent performance of Si in the band above 10keV due to the high particle background

High Frame Rate and High Time Resolution are Key Issues for Next Generation of X-ray Astronomical Imagers



- realize very low non-Xray BGD by anti-coincidence with surrounding scintillators
- event rate from the scintillators is about ~10kHz
- XRPIX is required to have time resolution much faster than ~10kHz.

Target Specification of the Device

Imaging	area ~ 15x45mm² pixel ~ 30-60µm□ (1" @ F=10m)	same performance as CCD
Energy Band	Req. I-40 keV, Goal 0.5-40 keV Backside Illumination Req. <Ιμm, Goal 0.Ιμm Full Depletion Req. >250μm	
Spectroscopy	ΔE : Req. < 300eV, Goal < 140eV @ 6keV ENC: Req. <10e-, Goal < 3e- \leftarrow Most Difficult	
Time Resolution	< 10µsec for the anti-coincidence with the rate of ~10kHz	
Max Count Rate	> 2kHz / detector for observation of bright X-ray sources	
	new feature	s with X-ray SOIPIX

Power Consumption in FEE

- Counting rate is \sim kHz even in the case of the brightest X-ray star.
- In the case of CCD
 - The pixel rate of CCD is ~MHz (~Mpixel / sec).
 - Most of the pixels have no X-ray information.
 - The power consumption in FEE is proportional to the pixel rate of ~MHz.
- In the case of the Event Driven type
 - Only pixels having X-ray information are read out.
 - The power consumption in FEE is proportional to the counting rate of ~kHz.
- The Event Driven type of detector has advantages in terms of power consumption in FEE.

Event Driven Readout



Pixel and Peropheral Circuits (since XRPIX5) 13



Results from the recent developments

Two Readout Modes:

- Frame Readout Mode
 Read out all pixels serially without using the trigger function.
- Event Driven Readout Mode Read out 8x8 pixels with a triggered pixel in the center using the trigger function.

Imaging in Event-Driven Mode (XRPIX5b)



Cd-109,Vbb=10V, Room Temp. (movie in 10 times speed)

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Capability of event rate > 500Hz is Confirmed

Improvement of Spectral Performance in Frame Mode



Comparison of Frame and Event-Driven Modes¹⁷



• in-pixel circuit consists of analog and digital circuits

 operation of digital circuit influences the analog signal in the eventdriven readout mode

Takeda+2015 JINST, Takeda+2013 IEEE/NSS, Takeda Ph.D Thesis, 20140814_takeda_v0.pdf

Double SOI Structure



Two causes making the spectral performance worse in the Event Driven mode

- I) analog and digital circuits have a common power supply line (common impedance coupling) \Rightarrow modified the power lines
- 2) crosstalk between digital circuit and BPW (electrically connecting to the sense-node) \Rightarrow "Double SOI"



Ohmura+2016 NIM A

Double SOI Structure to increase the Gain

- We found that the gain of the in-pixel CSA was lower than the designed value.
- This is probably because there is parasitic capacitance around the inpixel CSA.
- We increased the gain about a factor of two by cutting the parasitic capacitance with the DSOI structure.





Event-Driven Mode with DSOI ^{[20}

Frame readout mode

Event-Driven readout mode



No correction of inter-pixel gain variations

• The spectral performance in the frame mode was successfully improved.

• The performance in the event-driven mode is now close to the one in the frame mode.

20171129_XR6D_ed_fr_spectrum_v0.pdf, Hayashi, Takeda+2017

Gain - Readout Noise



Summary

- We are developing scientific SOIPIX detectors for particle physics, astrophysics, photon science etc.
- We introduced the status of the development of Event Driven X-ray astronomy SOIPIX (XRPIX).
- Introduction of the DSOI structure (and PDD structure ⇒ Kawahito-sensei's talk) successfully suppress the interference between the circuit layer and sensor layer.
- We reached ENC of ~30-35e (rms) and ΔE of ~300eV (FWHM) at 6keV in the Event Driven readout mode.



Lapis Semiconductor 0.2 μm FD-SOI Pixel Process

Process	0.2 μm Low-Leakage Fully-Depleted SOI CMOS
	1 Poly, 5 Metal layers.
	MIM Capacitor (1.5 fF/um ²), DMOS
	Core (I/O) Voltage = 1.8 (3.3) V
SOI wafer	Diameter: 200 mm ϕ , 720 μ m thick
(single)	Top Si : Cz, ~10 Ω -cm, p-type, ~40 nm thick
	Buried Oxide: 200 nm thick
	Handle wafer: Cz (n) ~700 Ω -cm,
	$FZ(n) > 2k \Omega$ -cm, $FZ(p) \sim 25 k \Omega$ -cm etc.
Backside	Mechanical Grind, Chemical Etching, Back side
process	Implant, Laser Annealing and Al plating

History of XRPIX Series



Peripheral Readout (since XRPIX5)



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Pinned Depleted Diode, a new device structure

New Device Structures : Pinned Depleted Diode (PDD)²⁷



Event-Driven Mode with PDD

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Single-pixel events collected from 8x8 Pixels No correction of inter-pixel gain variations

The spectral performance is similar to the one of DSOI version.
The tail component with PDD is smaller than the one with DSOI.

XR6E_spectrum_harada_171127_v1.pdf, Harada, Kamehama, Hayashi+2017

Dark Current



What makes the difference ?



